

ABSTRACT

A plurality of elements such as a resistor (10), capacitor (20), and coil (30) and switches 41 to 44 for connecting these elements are formed integrally on a substrate 1 and the elements are made freely connectable to form a MEMS array. The switches 41 to 44 used may be transistor switches or mechanical switches. It is possible to produce a MEMS device by replacing the on/off states of the switches 41 to 44 of the MEMS array with short-circuited/open states of the interconnects.